

<b>Notice of References Cited</b>	Application/Control No. 10/070,286	Applicant(s)/Patent Under Reexamination BENZEL ET AL.	
	Examiner Anita K Alanko	Art Unit 1765	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,359,276	03-2002	Tu, Xiang Zheng	250/338.1
	B	US-5,352,635	10-1994	Tu et al.	438/53
	C	US-2004/0195096	10-2004	Tsamis et al.	204/426
	D	US-5,139,624	08-1992	Searson et al.	205/656
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	RU 2099813 C1	12-1997	Russian Federat	PEREVOSHCHIKOV et al.	H01L 21/308
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Lammel, G. et al "Free-standing, mobile 3D porous silicon microstructures" Sensors and Actuators A Physical, 85, pp 356-360, August 25, 2000.
	V	
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.